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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No. 08/846,671
Filing Date April 30, 1997
Inventor Kei-Yu Ko
Assignee Micron Technology, Inc.
Group Art Unit 1763
Examiner George Goudreau
Attorney's Docket No. MI22-2041
Title: Undoped Silicon Dioxide as Etch Stop for Selective Etch of
 Doped Silicon Dioxide

**RESPONSE TO MARCH 3, 2003 CONFERENCE WITH EXAMINER AND
SUPPLEMENTAL RESPONSE TO DECEMBER 5, 2002 OFFICE ACTION**

To: Commissioner for Patents
 Washington, D.C. 20231

VIA EXPRESS MAIL

From: Mark Matkin (Tel. 509-624-4276; Fax 509-838-3424)
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Responsive to the Conference with the examiner, held on March 3,
2003, Applicant amends and remarks as follows:

AMENDMENTS